

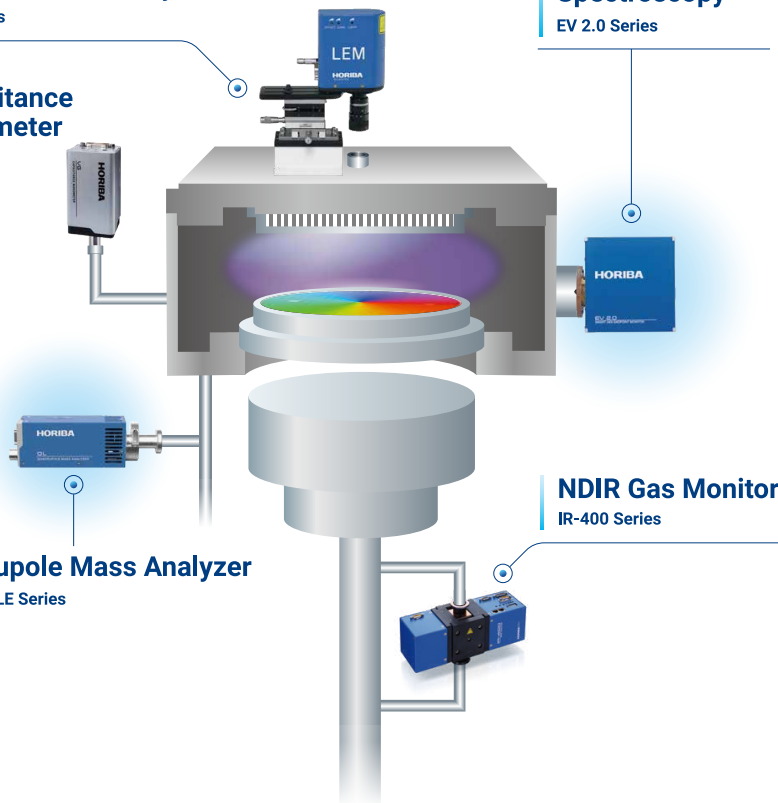
# Endpoint Detection

## Endpoint Detection

**Laser Interferometry**  
LEM Series

**Capacitance Manometer**  
VG Series

**Optical Emission Spectroscopy**  
EV 2.0 Series



**Quadrupole Mass Analyzer**  
MICROPOLE Series

**NDIR Gas Monitor**  
IR-400 Series

## Detect end points by monitoring plasma

**Plasma monitor**  
*EV 2.0 Series*

- Three models available to meet a wide range of analytical needs
- Provides end point detection
- Fast sampling function



## Monitor etch depth and film thickness

**Laser interferometer**  
*LEM Series*

- Ideal for vacuum chamber condition management and process monitoring



## Optimize chamber cleaning process

**Gas monitor for endpoint detection**  
*IR-400 Series*

- Cleaning end point detection
- Real time monitoring of exhaust gas components
- Contributes to reducing global warming gas use

